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REV. 1-84

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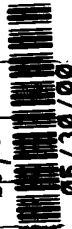
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Jahr et al.

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09/583229



U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
8	AA	5 757 494	3/26/98	Green et al.	356	369	
	AB	5 756 212	1/6/98	Thompson et al.	364	525	
	AC	5 582 646	12/10/96	William et al.	118	708	
	AD	6 034 777	3/7/00	Jahr et al.	356	369	
	AE	5 373 359	12/13/94	William et al.	356	328	
	AF	5 666 201	9/9/97	Jahr et al.	356	369	
	AG	5 521 706	5/28/96	Green et al.	356	369	
	AH	5 504 582	4/2/96	Jahr et al.	356	369	
	AI	4 516 855	5/14/85	Ko-Th	356	367	
	AJ	5 877 859	3/2/99	Aspner et al.	356	364	
49	AK	5 798 883	7/25/98	Aspner et al.	356	369	

FOREIGN PATENT DOCUMENTS

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EXAMINER: *Galow J. H.* DATE CONSIDERED: *5/13/03*

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USCOMM-DC 10-1997

Form PTO-1449  
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EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JS	AA	5 333 052	7/26/94	Fineman	356	369	
	AB	5 668 526	3/4/97	Pine-ha-Cerle et al.	356	369	
	AC	5 793 486	8/11/98	Lacey et al.	356	73	
	AD	4 636 075	1/13/87	Kneller-borg	356	336	
	AE	4 893 932	1/16/90	Kneller-borg	356	369	
	AF	4 668 866	5/26/87	A-Thon	252	225	
JS	AG	5 917 594	6/29/95	A-Thon	356	327	
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES
AL						
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PLEASE USE THE FOLLOWING FOR PTO FORM 1449 FOR SCIENTIFIC PAPERS

28 "Automatic Rotating Element Ellipsometers: Calibration, Operation and Real-Time Applications", Collins, Rev. Sci. Instrum, 61(8) (1990), provides general insight.

"Regression Calibration Method for Rotating Element Ellipsometers", Thin Solid Films, Johs, 234 (1993) is disclosed as it describes a mathematical regression based approach to calibrating ellipsometer systems.

"Systematic and Random Errors in Rotating-Analyzer Ellipsometry", Nijs & Silfhout, J. Opt. Soc. Am. A., Vol. 5, No. 6, (June 1988), describes a first order mathematical correction factor approach to accounting for window effects in Rotating Analyzer ellipsometers.

"Systematic Errors in Rotating-Compensator ellipsometry", Kleim et al., J. Opt. Soc. Am., Vol 11, No. 9, (Sept. 1994) describes first order corrections for imperfections in windows and compensators in Rotating Compensator ellipsometers.

"Instrumental and Computational Advances for Real-time Processes Control Using Spectroscopic Ellipsometry", Pickering et al, Int. Conf. on Metrology and Characterization for VSLI Tech., NIST, (March 1998).

"Unified Analysis of Ellipsometry Errors Due to Imperfect Components Cell-Window Birefringence, and Incorrect Azimuth Angles", Azzam & Bashara; J. of the Opt. Soc. Am., Vol 61, No. 5, (May 1971).

"Analysis of Systematic Errors in Rotating-Analyzer Ellipsometers", Azzam & Bashara; J. of the Opt. Soc. Am., Vol. 64, No. 11, (Nov. 1974).

"The Influence of Cell Window Imperfections on the Calibration and Measured Data of Two Types of Rotating Analyzer Ellipsometers", Azzam & Bashara; J. of the Opt. Soc. Am., Vol. 61, No. 6, (Nov. 1971).

"The Influence of Cell Window Imperfections on the Calibration and Measured Data of Two Types of Rotating Analyzer Ellipsometers", Straaher et al., Surface Sci., North Holland, 96, (1980),

"In Situ Multi-Wavelength Ellipsometric Control of Thickness and Composition of Bragg Reflector Structures", by Herzinger, Johs, Reich, Carpenter & Van Hove, Mat. Res. Soc. Symp. Proc., Vol. 406, (1996).

30 "A New Calculus For The Treatment Of Optical Systems", Jones, J.O.S. A., Vol. 31, (July 1941).

Galileo S. A. 8/13/03